

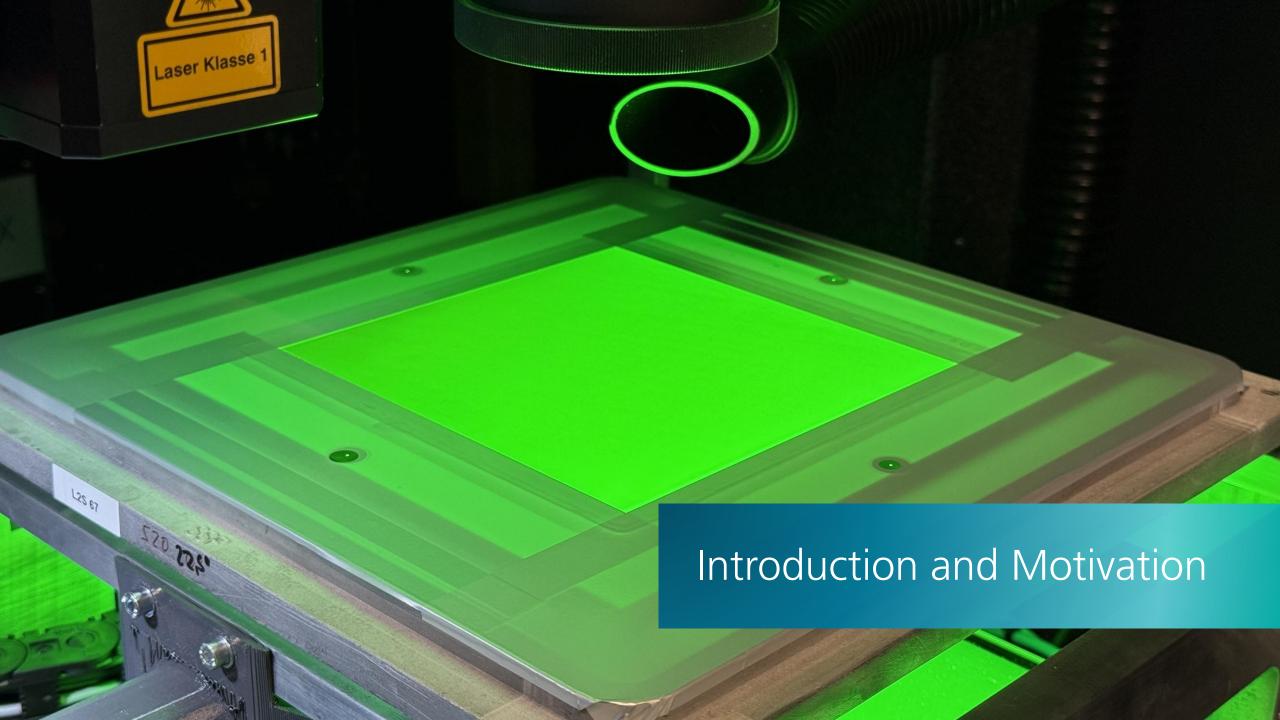


Progress in Fine Line Metallization:
Optimization of laser processing during screen production

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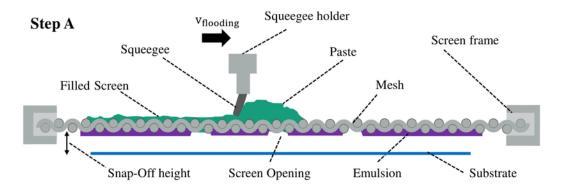
October 21st 2025, Berlin
13th Metallization and Interconnection Workshop

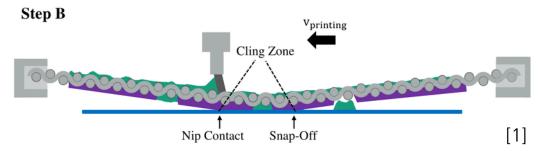


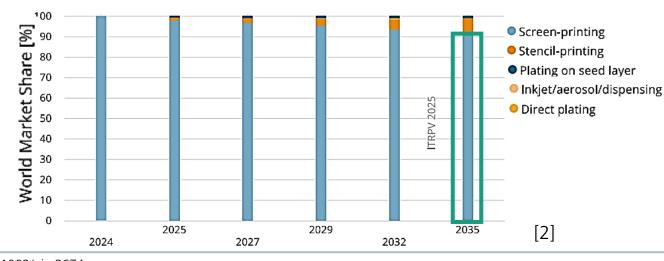
Fine-line Screen Printing

- Reliable
- Robust
- Cost effective

 Expected to remain leading method of metallization over the next decade



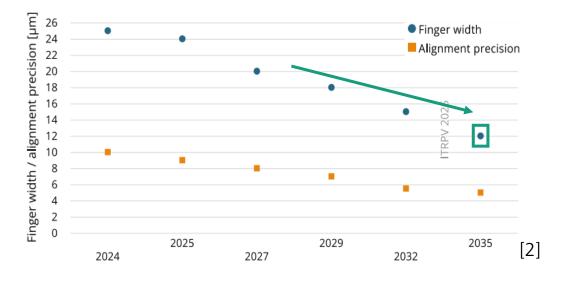


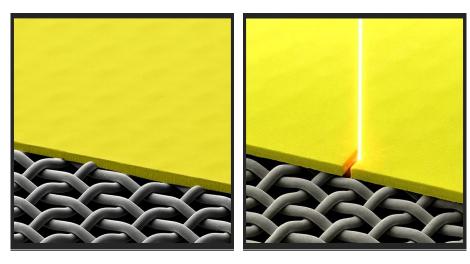




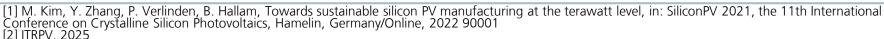
Screen structuring with laser technology

- To achieve terawatt level PV production sustainably, silver consumption must be reduced^[1]
- Finger width of front side metalliztion expected to reach
 12 µm in 2035
- This goal can be realized by optimizing the screen structuring process through:
 - Laser structuring
- Technology introduced in 2018^[4]
- Aim: To further optimize this process and obtain finer openings









3 Al generated image

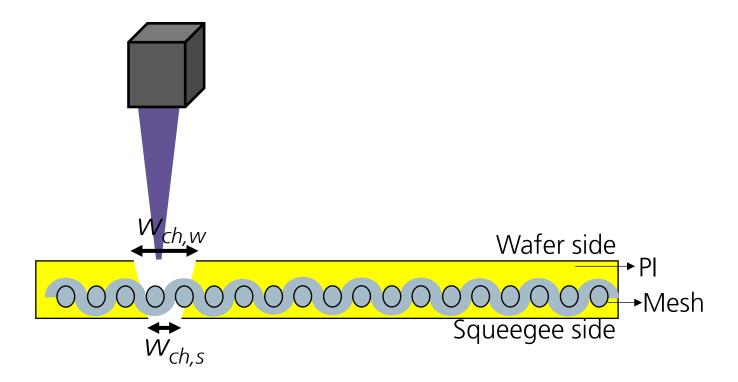
4] Brave C&H supply Co [Online], https://en.bch.com.tw/, Accessed 14.10.25.



Screen structuring with laser technology: Advantages

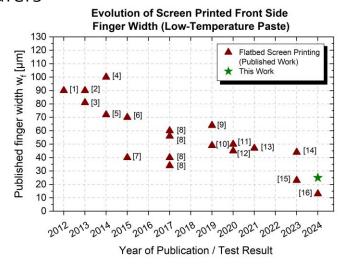
Advantages:

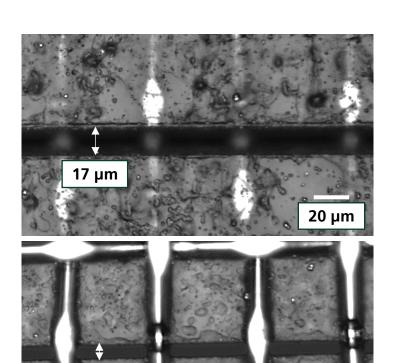
- Flexibility to laser any barrier layer material
- Tapering effect can be tuned
- Faster than "traditional" photolithography
- Precision: Could be used to create openings between wires in case of knotless screens
- Potentially finer openings (i.e. for contact fingers)

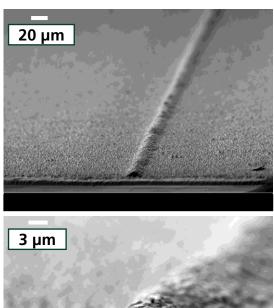


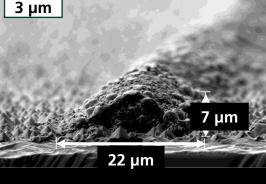
Laser structuring of screens, published results

- Successful laser structuring of full layout in 10 minutes on 520/11/0° screen and hybrid barrier layer
- Channel opening was tapered
- Average finger width of 23 µm measured on M2
 HJT wafers

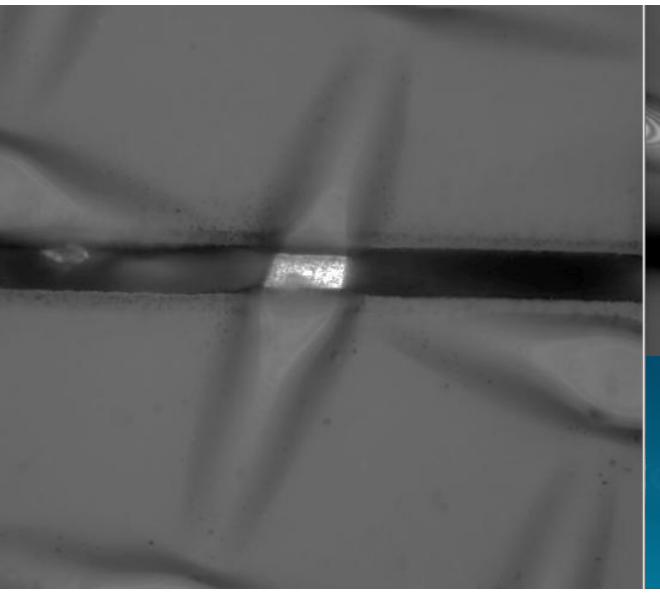


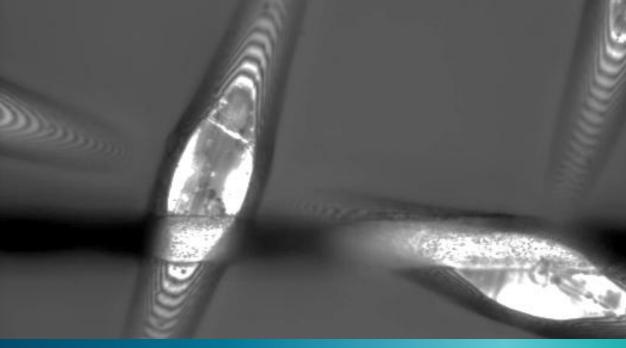










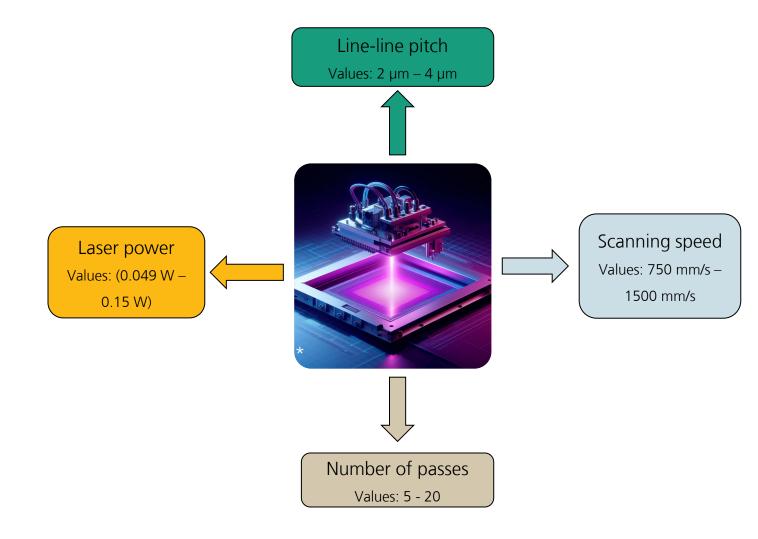


Parameters varied

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- Laser structuring process is highly dependent on several critical input laser parameters
- These parameters are crucial to determine the desired screen opening width and taper

Following laser input parameters were varied:

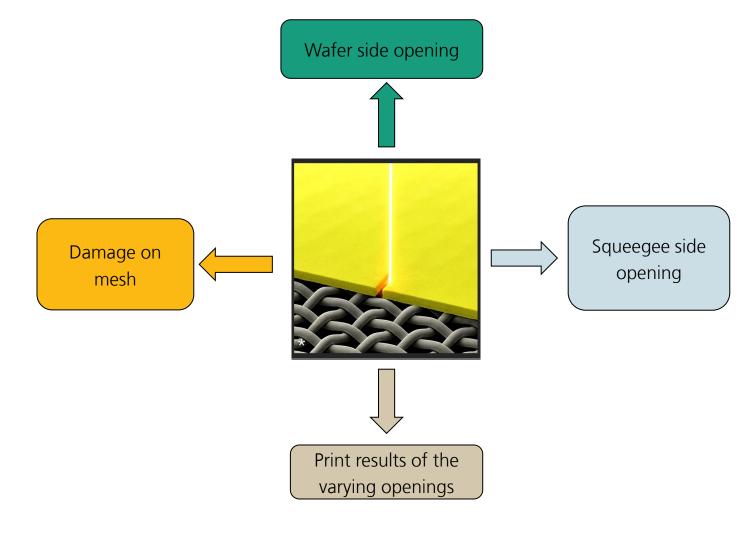




Fraunhofer

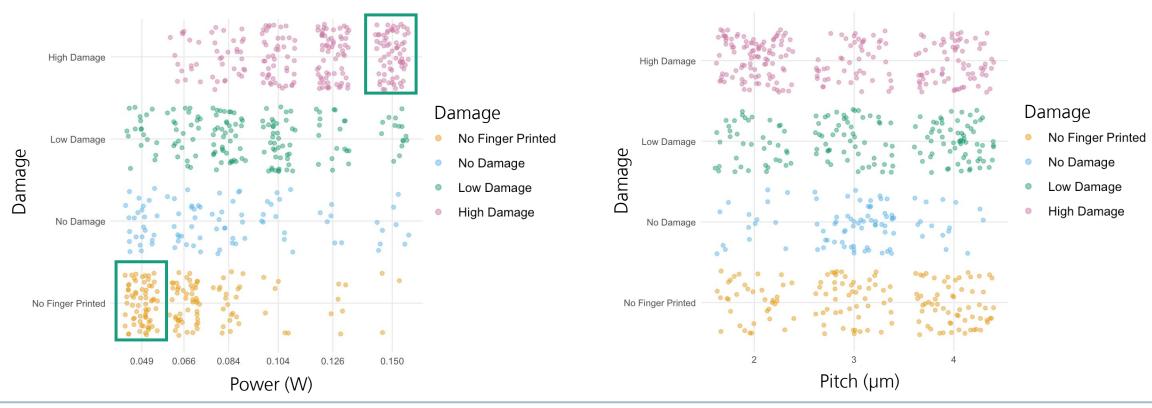
Parameters varied

Output parameters measured were:



Results

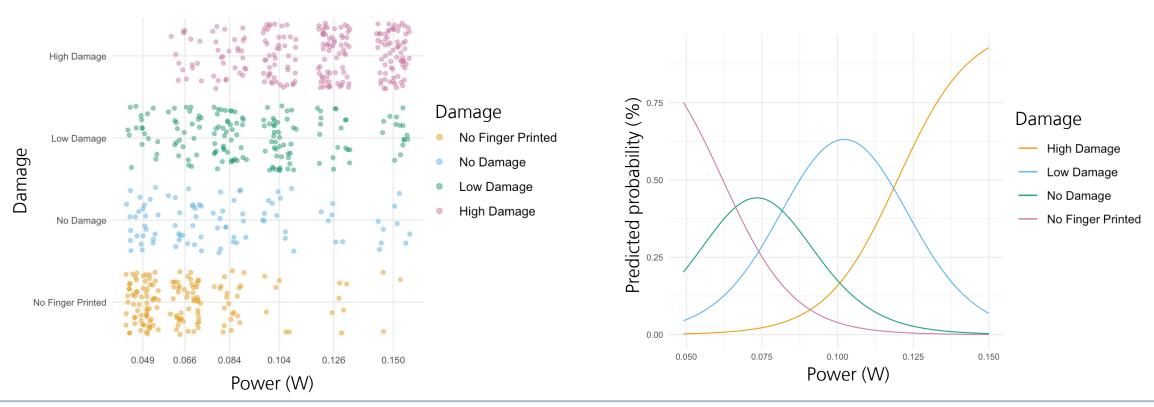
Power had the highest impact on the screen structuring process





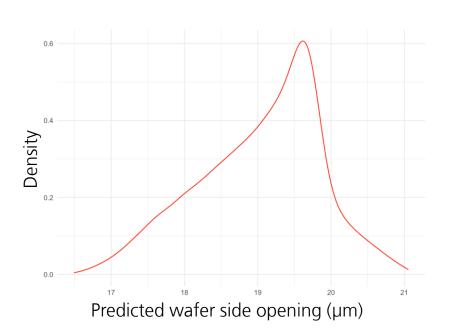
Results

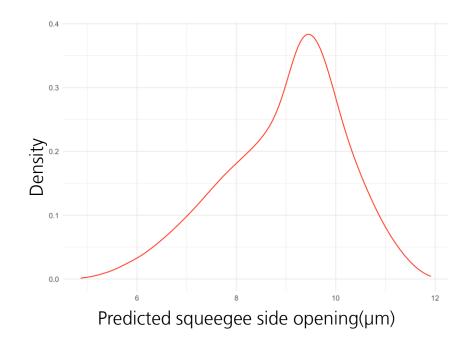
- Power had the highest impact on the screen structuring process
- <u>Predicted probability</u>: Find parameter combinations that cause least damage to screen and successful print is expected



Results

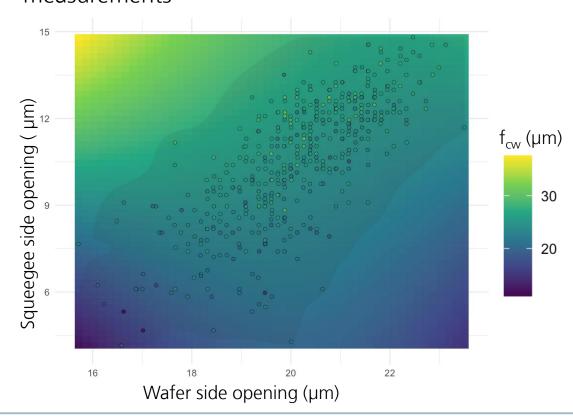
• Predicted probability of the input laser parameters yields predicted wafer and squeegee side measurements that cause less damage to the mesh





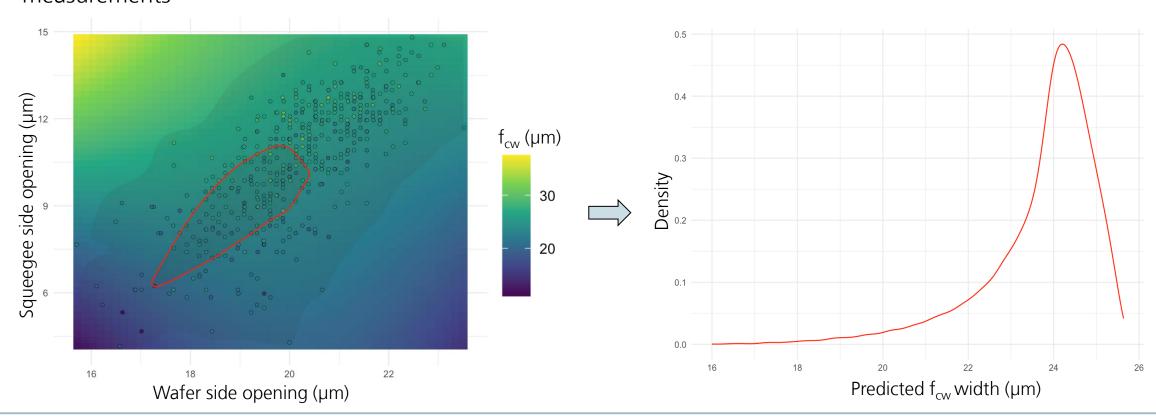
Results

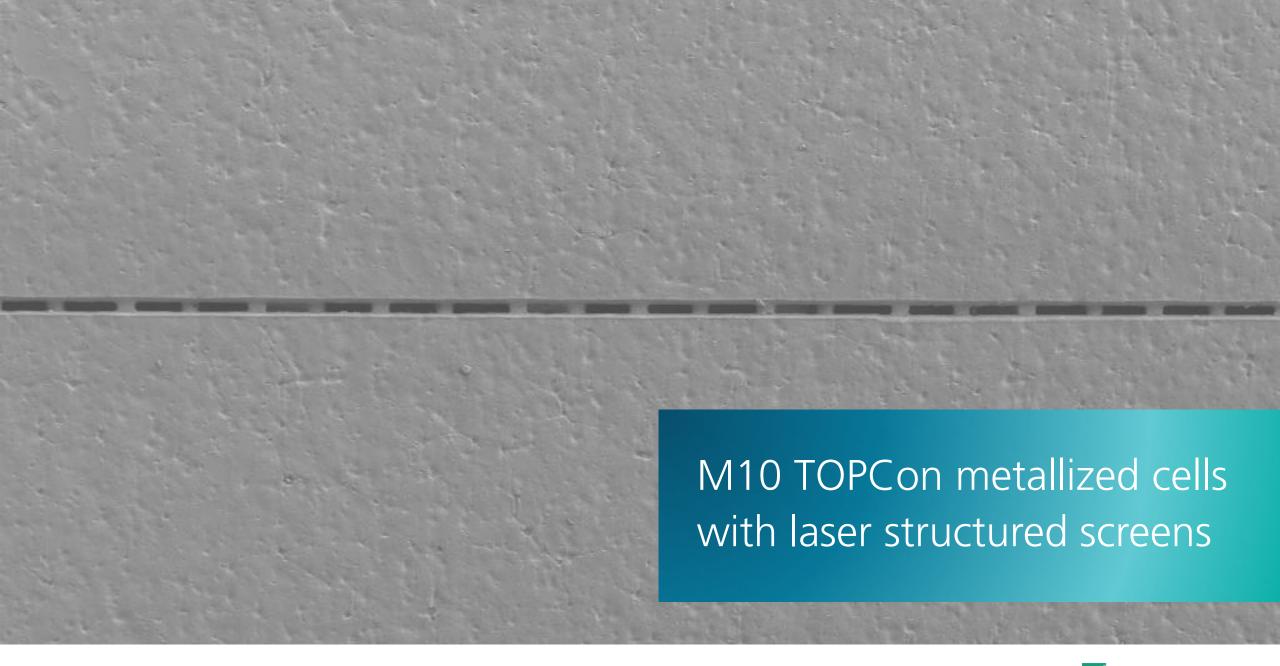
 Predicted probability of the wafer and squeegee side values yields predicted finger core width (f_{cw}) measurements



Results

 Predicted probability of the wafer and squeegee side values yields predicted finger core width (f_{cw}) measurements





M10 TOPCon metallized cells with laser structured screens

Aim and experimental setup

Aim:

Compare in-house lasered screens with an industry standard screen

Experimental setup:

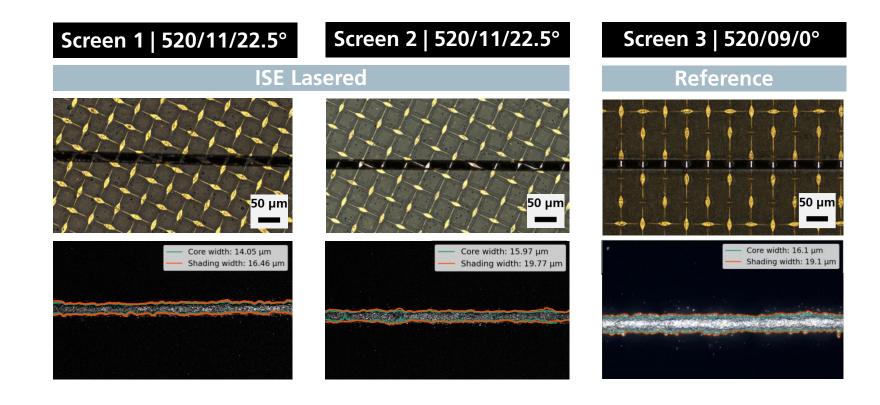
- Screen/paste variation:
 - Fraunhofer ISE TOPCon precursors (M10)
 - Constant screen opening width of 20 µm
 - High-performance partially diluted Ag paste (B)

Screen 1 (ISE lasered)	Screen 2 (ISE lasered)	Screen 3 (ref)
520/11/22.5°	520/11/22.5°	520/9/0°
20	20	20
В	В	В
40 mins	40 mins	N/a
	(ISE lasered) 520/11/22.5° 20 B	(ISE lasered) (ISE lasered) 520/11/22.5° 520/11/22.5° 20 20 B B

Experimental setup – Overview of screen variations for the conducted TOPCon fine line test batch.

M10 TOPCon metallized cells with laser structured screens

Screen printing results



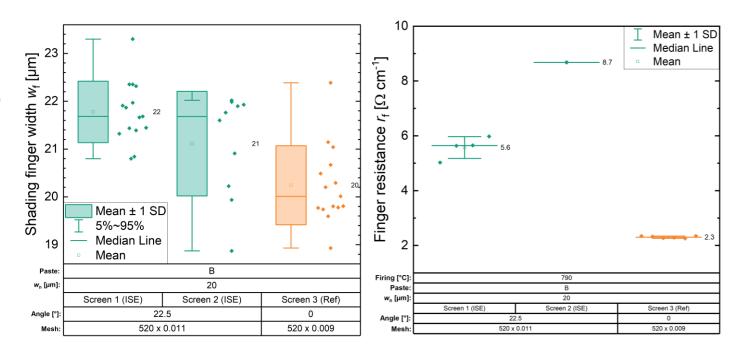
M10 TOPCon metallized cells with laser structured screens

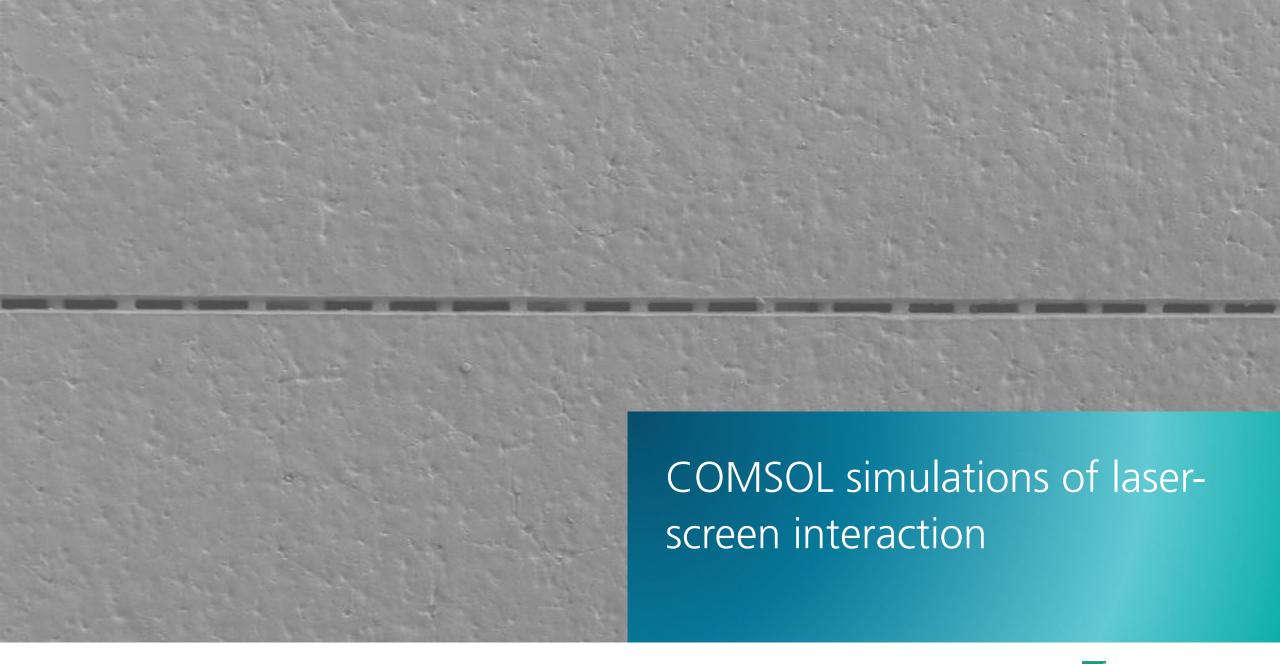
Screen printing results

- Shading width of printed fingers comparable with industry reference Screen 3
- However, higher finger resistance compared to industry standard due to the use of angles screens

Future Outlook:

 Currently working on realizing laser openings in knotless screens





COMSOL simulations of laser-screen interaction

Introduction and Motivation

Processes Involved during material interaction with a laser:

Energy absorption and heat transfer

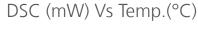
Material decomposition and vaporization

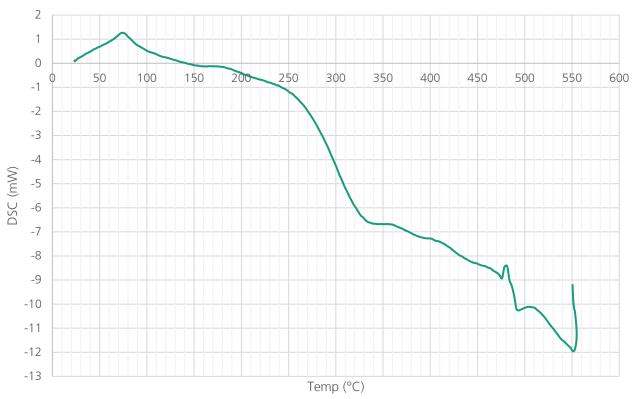
Interface effects and surface recession

- Aim
 - To simulate a large parameter space and corroborate with the experimental findings
 - Advantage: Reducing parameter variation experiments and reducing screens used

COMSOL simulations of laser-screen interaction

Methodology: Differential Scanning Calorimetry (DSC) measurements





- Ablation Temperature: 185 °C
- Latent Heat: 685.75 J/g
- Laser parameters used for simulation

Laser power: 0.17 Watt

Pulse duration: 15 Picoseconds

Wavelength: 355 nm

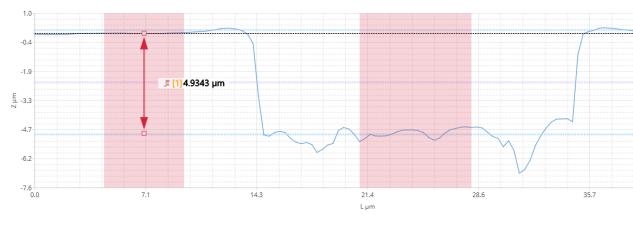
Focal spot size radius: 4 μm

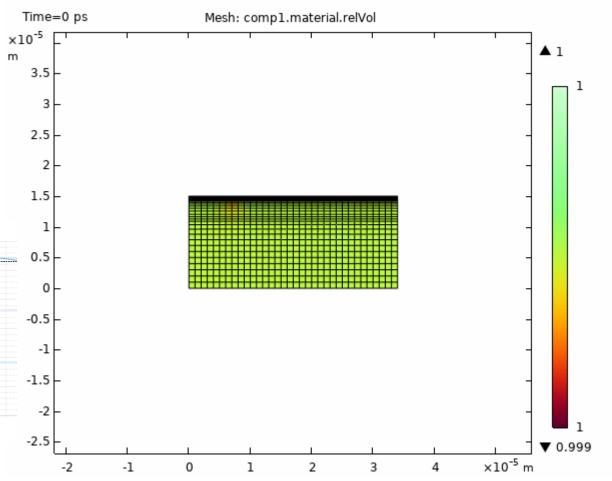
Scanning speed: 3 m/s

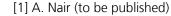
COMSOL simulations of laser-screen interaction

Results: 2D simulation

- Successful simulation of ablation mechanism on a polyimide layer
- At pass = 1, material of 5 μm removed according to simulation
- Comparable with real life results obtained from 3D microscopy (below)







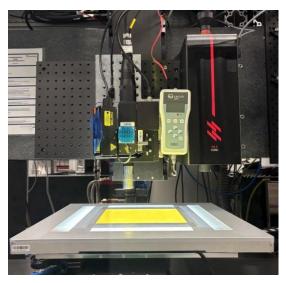
Summary and Future Outlook

Results:

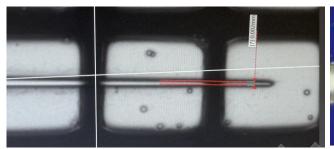
- Successful structuring of fine line openings = 20 μm on screens
- Finger widths of 21 µm printed on M10 TOPCon cells
- 2D COMSOL simulation of ablation by pulsed laser of screen similar to experimental results

Next Steps:

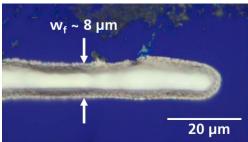
- Using the automated microscope to detect damages on wires
- Conducting print test on wafers with knotless screens with a screen opening of 1 µm with optimized pastes
- Conducting 3D COMSOL simulation of laser-screen interaction to gauge the taper observed in experiments



Setup of automated microscope at Fraunhofer ISE for faster and accurate screen characterization



Ultra narrow tapered channel in between two wires (500-05 mesh)



Screen-Printed ultra fine contact with $w_f \sim 8 \mu m$



Thank you for your attention!

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